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**PATENT APPLICATION**

**RESPONSE UNDER 37 CFR §1.114  
TECHNOLOGY CENTER ART UNIT 1762**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re the Application of

Shunichi SEKI et al.

Group Art Unit: 1762

Application No.: 09/701,534

Examiner: M. B. Cleveland

Filed: November 30, 2000

Docket No.: 107291

For: METHOD FOR FORMING SILICON FILM AND INK COMPOSITION FOR INK  
JET

**AMENDMENT UNDER 37 CFR §1.111**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In reply to the September 16, 2004 Office Action, please consider the following:

**Amendments to the Claims** are reflected in the listing of claims; and

**Remarks.**